

A B S T R A C T

An exposure apparatus comprises a container-mount,
on which a holder container that can contain a substrate
holder in a sealed manner and that has a door is mounted,
5 the door being able to open and close; an open-close
mechanism that opens and closes the door in a manner that
the inside of the container mounted on the container-
mount is isolated from the outside; and a transport
system that exchanges such a holder on a stage with
10 another holder in the container when the open-close
mechanism has opened the door. Therefore, the transport
system can exchange such holders in a short time in a
manner that the inside of the apparatus is isolated from
the outside. Accordingly, the down time of the apparatus
15 can be shortened, and the cleanliness of the holders can
be maintained all the time. As a result, the productivity
of devices such as semiconductor devices can be improved.